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Mark: AFS

AFS

US Serial Number:	88225504	Application Filing Date:	Dec. 11, 2018		
US Registration Number:	5975022	Registration Date:	Feb. 04, 2020		
Filed as TEAS RF:	Yes	Currently TEAS RF:	Yes		
Register:	Principal				
Mark Type:	Trademark				
TM5 Common St		LIVE/REGISTRATION	I/Issued and Active		
Descriptor:		The trademark applica	tion has been registered with the Office.		
Status:	Status: Registered. The registration date is used to determine when post-registration maintenance documents are due.				

Status Date: Feb. 04, 2020

Publication Date: Nov. 19, 2019

### **Mark Information**

Mark Literal AFS Elements:

Standard Character Yes. The mark consists of standard characters without claim to any particular font style, size, or color. Claim:

Mark Drawing 4 - STANDARD CHARACTER MARK Type:

## **Foreign Information**

Priority Claimed: Yes

Foreign 2018-087135 Application Number:

Foreign 6163250 Registration Number:

Foreign JAPAN Application/Registration Country: Date: Foreign Jul. 19, 2019 Registration Date:

**Application Filing** 

Foreign Expiration Jul. 19, 2029 Date:

Foreign Jul. 04, 2018

## **Goods and Services**

#### Note:

The following symbols indicate that the registrant/owner has amended the goods/services:

- Brackets [..] indicate deleted goods/services;
- Double parenthesis ((..)) identify any goods/services not claimed in a Section 15 affidavit of incontestability; and
- Asterisks \*..\* identify additional (new) wording in the goods/services.

For: Machines and structural parts therefor for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid controllers being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid measurement apparatus being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid flow controllers being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid flow controllers being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid flow meters being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid flow sensors being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid flow sensors being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid flow distributors being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid flow distributors being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid flow distributors being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, di

International Or - Primary Class       U.S Classeles: 103, 019, 021, 023, 031, 034, 035         Class Status:       ACTVE         Basis:       44(e)         For:       Messuring or testing machines and instruments, namely, technical measuring, testing and checking apparatus and instruments for measuring, testing and checking the quantity of fluid flow, fluid pressure, fluid concentration, gas concentration or gas and liquids; fluid flow controllers for use in controlling a gas concentration fluid flow controllers for regulating the flow velocity of fluid for supplying to multiple supply lines; fluid flow controllers for regulating the flow velocity of fluid and passes; fluid velocity measurement pluid flow controllers for regulating fluid flow, fluid gas concentration, industrial processes, pressure meters, namely, pressure fluid, early agas concentration industrial processes; pressure meters, namely, pressure fluid flow controllers for regulating fluid flow, flow regulators for controlling the flow velocity of fluid and gases; fluid velocity measurement pluid flow operations; concentration pressure, flow regulators for controlling the flow velocity of fluid and gases; fluid velocity measurement pluid flow operations; concentration, fluid flow setter industrial processes; pressure meters, namely, pressure fluid exercent measuring fluid flow, fluid pressure, fluid flow operations; exercentration, resure setter industrial processes; presure meters, namely, pressure fluid, exercent meters, laborate in industrial processes; presure meters, namely, pressure fluid, exercent meters, laborate in industrial processes; presure meters, namely, pressure, fluid flow operations; orecontrations, concentration, concentration, concentrati		organic electroluminescent elements; fluid flow ratio controllers being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid velocity controllers being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid velocity measurement apparatus being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; pressure controllers being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; pressure controllers being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; pressure controllers being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; pressure sensors being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; concentration controllers being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; concentration meters being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; concentration motirs being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; concentration monitors being structural parts of machines			
Basis: 4(e)         For:       Messuring or testing machines and instruments, namely, februical messurum, ludi operature, lu		007 - Primary Class U.S Class(es): 013, 019, 021, 023, 031, 034, 035			
For:       Measuring or testing machines and instruments, namely, technical measuring, testing and checking the quantity of fluid flow, fluid pressure, fluid concentration, agas concentration of gas and liquids; fluid flow control inequines and instruments for use in controlling a gas concentration, fluid flow meters; fluid flow control inequines and instruments for use in controlling a gas concentration fluid flow meters; fluid flow control inequines and instruments for use in controlling a gas concentration, fluid flow meters; fluid flow control machines and instruments for use in controlling a gas concentration, fluid flow meters; fluid flow control inequines and instruments for use in controlling a gas concentration, fluid flow meters; fluid flow control inegrations; namely, flow regulators for selecting and distributing multiple supply ines; fluid flow controlling is gain acconcentration, pressure sensors; concentration controllers, namely, flow regulators for selecting and distributing multiple supply ines; fluid flow, fluid pressure, fluid sensities; fluid flow, fluid pressure, fluid sensities; fluid flow, fluid pressure, fluid sensities; fluid flow, fluid pressure fluid, and gases; fluid selection; sonsors is use and instruments for use in measuring fluid flow, fluid pressure, fluid concentration, gas concentration mater; isboratory aparatuses and instruments for use in measuring fluid flow, fluid pressure, fluid concentration, gas concentration mater; isboratory isboratory aparatuses and instruments for use in measuring fluid flow, fluid pressure, fluid concentration, gas concentration mater; isboratory aparatuses, analy, flow regulators for selecting and distributing the flow control fluid flow, fluid pressure, fluid concentration, concentration mater; isboratory aparatuses and instruments for use in measuring fluid flow, fluid pressure fluid concentration, concentration mater; isboratory aparatuses and instruments for use in measuring fluid flow, fluid pressure	Class Status:	ACTIVE			
measuring, testing and checking the quantity of fluid flow, fluid pressure, fluid concentration, gluid sciencettation of gas and liquids, fluid flow controllers for use in controllers, namely, gas concentration fluid flow controllers in use in controllers, namely, gas concentration fluid flow fluid flow, fluid	Basis:	44(e)	44(e)		
Class (es): Class Status: ACTIVE Basis: 44(e) Basis: 44(e) Basis Information (Case Level) Filed Use: No Filed ITU: No Currently Use: No Filed 44D: Yes Currently 44E: Yes Filed 44E: No Currently 66A: No Currently No Basis: No Filed 66A: No Currently No Basis: No Filed No Basis: No Current Owner (s) Information Owner Name: HORIBA STEC, Co., Ltd Owner Address: 2, Myanchigashi-cho Kisshoin, Minami-ku Kyoto-shi, Kyoto JAPAN 601-8510 Legal Entity Type: kabushiki kaisha (k.k.) State or Country JAPAN Where Organized: Current Owner (s) Information Attorney of Record Attorney of Record Attorney Finary IndemarkDocket (galemanhall.com Attorney Finary IndemarkDocket (galemanhall.com Attorney Finary IndemarkDocket (galemanhall.com	For:	measuring, testing and checking the quantity of fluid flow, fluid pressure, fluid concentration, gas concentration of gas and liquids; fluid flow controllers for use in controlling a gas concentration; fluid measurement apparatuses, namely, gas concentration meters; fluid flow controllers namely, automatic liquid-flow control machines and instruments for use in controlling a gas concentration; fluid flow meters; fluid flow sensors, namely, electronic sensors for measuring fluid flow; fluid distributors, namely, flow regulators for selecting and distributing multiple types of fluid to multiple supply lines; fluid flow tatic of fluid for supplying to multiple supply lines; fluid flow ratio controllers, namely, flow regulators for controlling the flow ratio of fluid for supplying to multiple supply lines; fluid flow controllers for regulating the flow velocity of liquids and gases; fluid velocity measurement apparatus; pressure controllers for controlling the pressure of liquid, semi-liquid, and gaseous substances in industrial processes; pressure meters, namely, electronic controllers for use in controlling a gas concentration; pressure sensors; concentration controllers, namely, electronic controllers for regulating liquid or gas concentration; pressure sensors;			
Class Status:       ACTIVE         Basis:       44(e)         Basis Information (Case Level)         Filed Use:         No       Currently Use:       No         Filed ITU:       No       Currently ITU:       No         Filed 44D:       Yes       Currently 66A:       No         Filed 44E:       No       Currently No Basis:       No         Filed No Basis:       No       Currently No Basis:       No         Filed No Basis:       No       Currently No Basis:       No         Current Owner(s) Information         Owner Address:       2, Miyanohigashi-cho Kisshoin, Minami-ku Kisshoin, Minami-			U.S Class(es): 021, 023, 026, 036, 038		
Basis: 4(e)         Basis Information (Case Level)         Filed Use: No       Currently Use: No         Filed HTU: No       Currently TU: No         Filed 44D: Yes       Currently 44E: Yes         Filed 44E: No       Currently 66A: No         Filed 66A: No       Currently No Basis: No         Filed No Basis: No       Currently No Basis: No         Current Owner(s) Information         Owner Name: HORIBA STEC, Co, Ltd       Koto-shi, Kyoto JAPAN 601-8510         Legal Entity Type:       xabushiki kaisha (k.k.)       State or Country JAPAN Where Organized:         Current of Record         Attorney Name:       Mark D. Alleman       Docket Number: HRB18404         Attorney Primary:       ItademarkDocket@ allemanhall.com       Authorized: Yes	. ,				
Basis Information (Case Level)         Filed Use: No       Currently Use: No         Filed TU: No       Currently ITU: No         Filed 44D: Yes       Currently 44E: Yes         Filed 44E: No       Currently 66A: No         Filed 66A: No       Currently No Basis: No         Filed No Basis: No         Current Owner(s) Information         Owner Name: HORIBA STEC, Co., Ltd         Owner Address: 2. Miyanohigashi-cho Kisshoin, Minami-ku Kyoto-shi, Kyoto JAPAN 601-8510         Legal Entity Type:       kabushiki kaisha (k.k.)       State or Country JAPAN Where Organized:         Attorney/Correspondence Information         Attorney of Record         Attorney Name:       Mark D. Alleman       Docket Number: HRB18404         Attorney Primary       TrademarkDocket@allemanhall.com       Attorney Email Yes Authorized:					
Filed Use: No       Currently Use: No         Filed ITU: No       Currently ITU: No         Filed 44D: Yes       Currently 44E: Yes         Filed 44E: No       Currently 66A: No         Filed 66A: No       Currently No Basis: No         Filed No Basis: No       Current Owner(s) Information         Owner Name: HORIBA STEC, Co., Ltd         Owner Address: 2, Miyanohigashi-cho         Kisphoin, Minami-ku         Kyoto-shi, Kyoto JAPAN 601-8510         Legal Entity Type:       kabushiki kaisha (k.k.)         State or Country JAPAN         Where Organized:         Chroney/Correspondence Information         Attorney Name:       Mark D. Alleman         Attorney of Record         Attorney Primary       TrademarkDocket@allemanhall.com         Email Address:       TrademarkDocket@allemanhall.com		Basis Ir	nformation (Case Level)		
Filed TUU:       No       Currently TUU:       No         Filed 44D:       Yes       Currently 44E:       Yes         Filed 44E:       No       Currently No Basis:       No         Filed 66A:       No       Currently No Basis:       No         Filed No Basis:       No       Currently No Basis:       No         Filed No Basis:       No       Currently No Basis:       No         Filed No Basis:       No       Currently No Basis:       No         Owner Name:       HORIBA STEC, Co., Ltd       Currently No Basis:       No         Owner Address:       2. Miyanohigashi-cho Kisshoin, Minami-ku Kyoto-shi, Kyoto JAPAN 601-8510       State or Country JAPAN Where Organized:       JAPAN         Legal Entity Type:       kabushiki kaisha (k.k.)       State or Country JAPAN       Mere Organized:         Attorney Mare:       Kark D. Alleman       Docket Number:       HRB18404         Attorney Primary:       TrademarkDocket@allemanhall.com       Attorney Email       Yes					
Filed 44D:       Yes       Currently 44E:       Yes         Filed 44E:       No       Currently 66A:       No         Filed 66A:       No       Currently No Basis:       No         Filed No Basis:       No       Currently No Basis:       No         Filed No Basis:       No       Currently No Basis:       No         Owner Name:       HORIBA STEC, Co., Ltd       Current Owner(s) Information         Owner Address:       2, Miyanohigashi-cho Kisshoin, Minami-ku Kyoto-shi, Kyoto JAPAN 601-8510       State or Country Where Organized:       JAPAN         Legal Entity Type:       kabushiki kaisha (k.k.)       State or Country Where Organized:       JAPAN         Currenty Name:       Mark D. Alleman       Docket Number:       HRB18404         Attorney Name:       Mark D. Alleman       Docket Number:       HRB18404         Attorney Primary       TrademarkDocket@ allemanhall.com       Attorney Email Attorney Email       Yes	Filed Use:	No	Currently Use: No		
Filed 44E:       No       Currently 66A:       No         Filed 66A:       No       Currently No Basis:       No         Filed No Basis:       No         Current Owner(s) Information         Owner Name:       HORIBA STEC, Co., Ltd         Owner Address:       2, Miyanohigashi-cho Kisshoin, Minami-ku Kyoto-shi, Kyoto JAPAN 601-8510         Legal Entity Type:       kabushiki kaisha (k.k.)       State or Country JAPAN Where Organized:         Current Owner Organized:       State or Country JAPAN         Legal Entity Type:       kabushiki kaisha (k.k.)       State or Country JAPAN         Muhorized:       State or Country JAPAN       State or Country JAPAN         Kyoto-shi, Kyoto JAPAN 601-8510       State or Country JAPAN       State or Country JAPAN         Legal Entity Type:       kabushiki kaisha (k.k.)       State or Country JAPAN         Mihor Dacket Number:       HRB18404       State or Country JAPAN         Mark D. Alleman       Docket Number:       HRB18404         Attorney Primary       TrademarkDocket@allemanhall.com       Attorney Email Yes Authorized;			-		
Filed 66A:       No       Currently No Basis:       No         Filed No Basis:       No       Current Owner(s) Information         Owner Name:       HORIBA STEC, Co., Ltd       State or Country       JAPAN         Owner Address:       2, Miyanohigashi-cho Kisshoin, Minami-ku Kyoto-shi, Kyoto JAPAN 601-8510       State or Country JAPAN Where Organized:         Legal Entity Type:       kabushiki kaisha (k.k.)       State or Country JAPAN Where Organized:         Current Of Record       Attorney of Record         Attorney Name:       Mark D. Alleman       Docket Number:       HRB18404         Attorney Primary Email Address:       TrademarkDocket@allemanhall.com       Attorney Email       Yes			Currently 44E: Yes		
Filed No Basis       No         Current Owner(s) Information         Owner Name       HORIBA STEC, Co., Ltd         Owner Address:       2, Miyanohigashi-cho Kisshoin, Minami-ku Kyoto-shi, Kyoto JAPAN 601-8510         Legal Entity Type:       kabushiki kaisha (k.k.)       State or Country Where Organized:         Japan       Attorney/Correspondence Information         Attorney Name:       Mark D. Alleman       Docket Number:       HRB18404         Attorney Primary       TrademarkDocket@ allemanhall.com       Attorney Email Yes Authorized:       Attorney Email Yes Authorized:			Currently 66A: No		
Current Owner(s) Information         Owner Name:       HORIBA STEC, Co., Ltd         Owner Address:       2, Miyanohigashi-cho Kisshoin, Minami-ku Kyoto-shi, Kyoto JAPAN 601-8510         Legal Entity Type:       kabushiki kaisha (k.k.)         State or Country Where Organized:         Current Overespondence Information         Attorney Name:       Mark D. Alleman         Mark D. Alleman       Docket Number:         HRB18404       Mark D. Alleman         Attorney Primary Email Address:       TrademarkDocket@allemanhall.com Attorney Email	Filed 66A:	No	Currently No Basis: No		
Owner Name:       HORIBA STEC, Co., Ltd         Owner Address:       2, Miyanohigashi-cho Kisshoin, Minami-ku Kyoto-shi, Kyoto JAPAN 601-8510         Legal Entity Type:       kabushiki kaisha (k.k.)         State or Country       JAPAN Where Organized:         Attorney/Correspondence Information         Attorney of Record         Attorney Name:       Mark D. Alleman         Mark D. Alleman       Docket Number:         HRB18404       Attorney Primary         Email Address:       TrademarkDocket@allemanhall.com	Filed No Basis:				
Owner Address:2, Miyanohigashi-cho Kisshoin, Minami-ku Kyoto-shi, Kyoto JAPAN 601-8510Legal Entity Type:kabushiki kaisha (k.k.)State or Country Where Organized:Attorney/Correspondence InformationAttorney of RecordAttorney Name:Mark D. AllemanAttorney PrimaryMark D. Alleman hall.comAttorney Email Address:Yes Authorized:		Curren	t Owner(s) Information		
Kisshoin, Minami-ku       Kisshoin, Minami-ku         Kyoto-shi, Kyoto JAPAN 601-8510         Legal Entity Type:       kabushiki kaisha (k.k.)       State or Country JAPAN         Mere Organized:       Attorney Correspondence Information         Attorney of Record         Attorney Name:       Mark D. Alleman       Docket Number:       HRB18404         Attorney Primary       TrademarkDocket@allemanhall.com       Attorney Email       Yes	Owner Name:	HORIBA STEC, Co., Ltd			
Where Organized:         Where Organized:         Attorney/Correspondence Information         Attorney of Record         Attorney of Record         Attorney Name: Mark D. Alleman       Docket Number: HRB18404         Attorney Primary Email Address:       TrademarkDocket@allemanhall.com       Attorney Email Yes         Authorized:       Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2">Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"Colspan="2"	Owner Address:	Kisshoin, Minami-ku			
Attorney/Correspondence Information         Attorney of Record         Attorney Name:       Mark D. Alleman       Docket Number:       HRB18404         Attorney Primary       TrademarkDocket@allemanhall.com       Attorney Email       Yes         Email Address:       TrademarkDocket@allemanhall.com       Attorney Email       Yes	Legal Entity Type:	kabushiki kaisha (k.k.)			
Attorney of Record         Attorney Name:       Mark D. Alleman       Docket Number:       HRB18404         Attorney Primary       TrademarkDocket@allemanhall.com       Attorney Email       Yes         Email Address:       Authorized:       Authorized:		A ttornov/C			
Attorney Name:     Mark D. Alleman     Docket Number:     HRB18404       Attorney Primary Email Address:     TrademarkDocket@allemanhall.com     Attorney Email     Yes		Auorney/C			
Attorney Primary       TrademarkDocket@allemanhall.com       Attorney Email Yes         Email Address:       Authorized:	Attorney of Record				
Email Address: Authorized:		Mark D. Alleman	Docket Number: HRB18404		
	Attorney Name:	Mark D. / Mornan			
	Attorney Primary Email Address:	TrademarkDocket@allemanhall.com	•		

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Correspondent e- Yes mail Authorized:

Domestic Representative - Not Found

## **Prosecution History**

Date	Description	Proceeding Number
Feb. 04, 2020	REGISTERED-PRINCIPAL REGISTER	
Nov. 19, 2019	OFFICIAL GAZETTE PUBLICATION CONFIRMATION E-MAILED	
Nov. 19, 2019	PUBLISHED FOR OPPOSITION	
Oct. 30, 2019	NOTIFICATION OF NOTICE OF PUBLICATION E-MAILED	
Oct. 11, 2019	APPROVED FOR PUB - PRINCIPAL REGISTER	
Sep. 17, 2019	TEAS/EMAIL CORRESPONDENCE ENTERED	68552
Sep. 17, 2019	CORRESPONDENCE RECEIVED IN LAW OFFICE	68552
Sep. 12, 2019	ASSIGNED TO LIE	68552
Sep. 06, 2019	TEAS RESPONSE TO OFFICE ACTION RECEIVED	
Mar. 08, 2019	NOTIFICATION OF NON-FINAL ACTION E-MAILED	6325
Mar. 08, 2019	NON-FINAL ACTION E-MAILED	6325
Mar. 08, 2019	NON-FINAL ACTION WRITTEN	82107
Mar. 08, 2019	ASSIGNED TO EXAMINER	82107
Jan. 03, 2019	NEW APPLICATION OFFICE SUPPLIED DATA ENTERED IN TRAM	
Dec. 14, 2018	NEW APPLICATION ENTERED IN TRAM	

## **TM Staff and Location Information**

#### TM Staff Information - None

File Location

Current Location: PUBLICATION AND ISSUE SECTION

Date in Location: Feb. 04, 2020



# AFS

Reg. No. 5,975,022 Registered Feb. 04, 2020 Int. Cl.: 7, 9 Trademark Principal Register



Andrei Jana

Director of the United States Patent and Trademark Office HORIBA STEC, Co., Ltd (JAPAN kabushiki kaisha (k.k.)) 2, Miyanohigashi-cho Kisshoin, Minami-ku Kyoto-shi, Kyoto, JAPAN 601-8510

CLASS 7: Machines and structural parts therefor for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid controllers being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid measurement apparatus being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid flow controllers being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid flow meters being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid flow sensors being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid distributors being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid flow distributors being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid flow ratio controllers being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid velocity controllers being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; fluid velocity measurement apparatus being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; pressure controllers being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; pressure meters being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; pressure sensors being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; concentration controllers being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; concentration meters being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent elements; concentration monitors being structural parts of machines for manufacturing semiconductors, solar cells, lightemitting diodes, displays, liquid crystal and organic electroluminescent elements; concentration sensors being structural parts of machines for manufacturing semiconductors, solar cells, light-emitting diodes, displays, liquid crystal and organic electroluminescent



elements

CLASS 9: Measuring or testing machines and instruments, namely, technical measuring, testing and checking apparatus and instruments for measuring, testing and checking the quantity of fluid flow, fluid pressure, fluid concentration, gas concentration of gas and liquids; fluid flow controllers for use in controlling a gas concentration; fluid measurement apparatuses, namely, gas concentration meters; fluid flow controllers namely, automatic liquid-flow control machines and instruments for use in controlling a gas concentration; fluid flow meters; fluid flow sensors, namely, electronic sensors for measuring fluid flow; fluid distributors, namely, flow regulators for selecting and distributing multiple types of fluid to multiple supply lines; fluid flow distributors, namely, flow regulators for selecting and distributing the flow rate of fluid for supplying to multiple supply lines; fluid flow ratio controllers, namely, flow regulators for controlling the flow ratio of fluid for supplying to multiple supply lines; fluid flow controllers for regulating the flow velocity of liquids and gases; fluid velocity measurement apparatus; pressure controllers for controlling the pressure of liquid, semi-liquid, and gaseous substances in industrial processes; pressure meters, namely, pressure meter indicators for use in controlling a gas concentration; pressure sensors; concentration controllers, namely, electronic controllers for regulating liquid or gas concentration; concentration meters; laboratory apparatuses and instruments for use in measuring fluid flow, fluid pressure, fluid concentrations, or gas concentrations

THE MARK CONSISTS OF STANDARD CHARACTERS WITHOUT CLAIM TO ANY PARTICULAR FONT STYLE, SIZE OR COLOR

PRIORITY CLAIMED UNDER SEC. 44(D) ON JAPAN APPLICATION NO. 2018-087135, FILED 07-04-2018, REG. NO. 6163250, DATED 07-19-2019, EXPIRES 07-19-2029

SER. NO. 88-225,504, FILED 12-11-2018

## REQUIREMENTS TO MAINTAIN YOUR FEDERAL TRADEMARK REGISTRATION WARNING: YOUR REGISTRATION WILL BE CANCELLED IF YOU DO NOT FILE THE DOCUMENTS BELOW DURING THE SPECIFIED TIME PERIODS.

#### **Requirements in the First Ten Years\*** What and When to File:

- *First Filing Deadline:* You must file a Declaration of Use (or Excusable Nonuse) between the 5th and 6th years after the registration date. See 15 U.S.C. §§1058, 1141k. If the declaration is accepted, the registration will continue in force for the remainder of the ten-year period, calculated from the registration date, unless cancelled by an order of the Commissioner for Trademarks or a federal court.
- *Second Filing Deadline:* You must file a Declaration of Use (or Excusable Nonuse) and an Application for Renewal between the 9th and 10th years after the registration date.\* See 15 U.S.C. §1059.

#### **Requirements in Successive Ten-Year Periods\*** What and When to File:

• You must file a Declaration of Use (or Excusable Nonuse) and an Application for Renewal between every 9th and 10th-year period, calculated from the registration date.\*

#### **Grace Period Filings\***

The above documents will be accepted as timely if filed within six months after the deadlines listed above with the payment of an additional fee.

\*ATTENTION MADRID PROTOCOL REGISTRANTS: The holder of an international registration with an extension of protection to the United States under the Madrid Protocol must timely file the Declarations of Use (or Excusable Nonuse) referenced above directly with the United States Patent and Trademark Office (USPTO). The time periods for filing are based on the U.S. registration date (not the international registration date). The deadlines and grace periods for the Declarations of Use (or Excusable Nonuse) are identical to those for nationally issued registrations. See 15 U.S.C. §§1058, 1141k. However, owners of international registrations do not file renewal applications at the USPTO. Instead, the holder must file a renewal of the underlying international registration at the International Bureau of the World Intellectual Property Organization, under Article 7 of the Madrid Protocol, before the expiration of each ten-year term of protection, calculated from the date of the international registration. See 15 U.S.C. §1141j. For more information and renewal forms for the international registration, see http://www.wipo.int/madrid/en/.

**NOTE:** Fees and requirements for maintaining registrations are subject to change. Please check the USPTO website for further information. With the exception of renewal applications for registered extensions of protection, you can file the registration maintenance documents referenced above online at h ttp://www.uspto.gov.

NOTE: A courtesy e-mail reminder of USPTO maintenance filing deadlines will be sent to trademark owners/holders who authorize e-mail communication and maintain a current e-mail address with the USPTO. To ensure that e-mail is authorized and your address is current, please use the Trademark Electronic Application System (TEAS) Correspondence Address and Change of Owner Address Forms available at http://www.uspto.gov.